

Camtek Condor 202M Inspection Tool

Manufacturer: Camtek
Model: Condor 202M

Specification:

Item #		Qty
PR1082800	<p>Condor 202M : Inspection system for pre and post Diced Wafers up to 200 mm 2" manual load and 4"to 8" frame sizes.</p> <p>Include special Chuck accommodating diced wafers with multi size enable. Switch between wafer frame size requires exchange of end-effector and chuck setting.</p> <p>Equipped with 6"-8" cassette for framed wafers and 2 end effectors. Includes ionizer [Ion] and HEPPA filter.</p> <ul style="list-style-type: none"> * Windows XP operating system * Die edit S/W (online and offline) * SPC (Yield maps, histograms and analysis for die level / wafer level / lot level) * Monochrome inspection camera * Review color camera * Magnifications option: 1x, 1.75x, 2.5x, 5x * Supports unframed wafer sizes 150mm (6") and 200mm (8") * Defect sensitivity of up to 1.8 micron pixel size * Conforms to CE, SEMI, ISO requirement 	1
PR2035100	<p>* Auto Loader 200mm (EFEM): Auto loader for 150mm (6") & 200mm (8"). Includes two load ports.Configuration by customer.</p> <p>Die Editing: employs a user-friendly graphical interface for recipe configuration that allows the user to define even and odd-shaped zones within the die area. Users can set the required different detection criteria areas for each zone. Off-line License available to provide remote operation support installed on separate computers.</p> <p>Automatic Wafer Loader: system accommodates 200mm (8") and 300mm (12") standard wafer cassettes and includes a Robot Arm and Wafer endeffector for 8" and 12" frame [customer selction one frame type standard]. Will support up to 2 cassettes.</p>	1

	<p>Color Defect Verification: accommodates 6.3x or 10x magnification verification lenses for defect review in color on screen. Lens magnification to be specified by customer at time of purchase.</p> <p>SPC (Statistic Process Control): generates comprehensive charts to assist the quality engineer in reducing manufacturing process variations, identifying root causes, and enhancing overall production yields.</p> <p>Fan Filter Unit (FFU): Enables class 100 mini environment</p>	
Item #	Optics	
PR2034204	10x Magnification Lense: Set of Objective lens x 10 and S/W for 0.9 microns pixels size. Approve application compliance and delivery time prior to order	1
PR2036400	Color camera and objective x 6.3: Built-in verification camera with 0.9 micron resolution	1
Item #	Software Packages	
PR2033800	Surface Inspection: Algorithms that find surface defects on predefined scan area.	1
PR2035400	Probe Mark Inspection: Algorithm reporting any kind of probe mark defect such as number of touch downs, area, proximity and breakouts from pad edges	1
PR2038900	Multi Recipe: Powerful inspection capability to scan any wafer with different focus and lighting condition. All scan results will be merged into one wafer map.	1
Item #	Wafer Maps	
PR2035900	<p>One Existing Wafer Map Format: AOI will import and update / create reports based on existing format.</p> <p>Formats available: STDF, Semi G85, TSK, TEL, EG_SORTNET, SINF, ESC, ITSK, TI_WWWM, STIF, SINF, KLA, etc.</p>	1
	OCR Barcode	
PR2062100	Top Optical Character Recognizer: Automatically reads the Wafer ID from the Top. Applicable for 200 mm systems	1
PR2050800	Double barcode reader for framed wafers -Automatically reads the barcode of a framed wafer. Enables reading any 2 barcode positions on the frame	1